

# Electrospun Silicon Nanowires as Lithium Anodes

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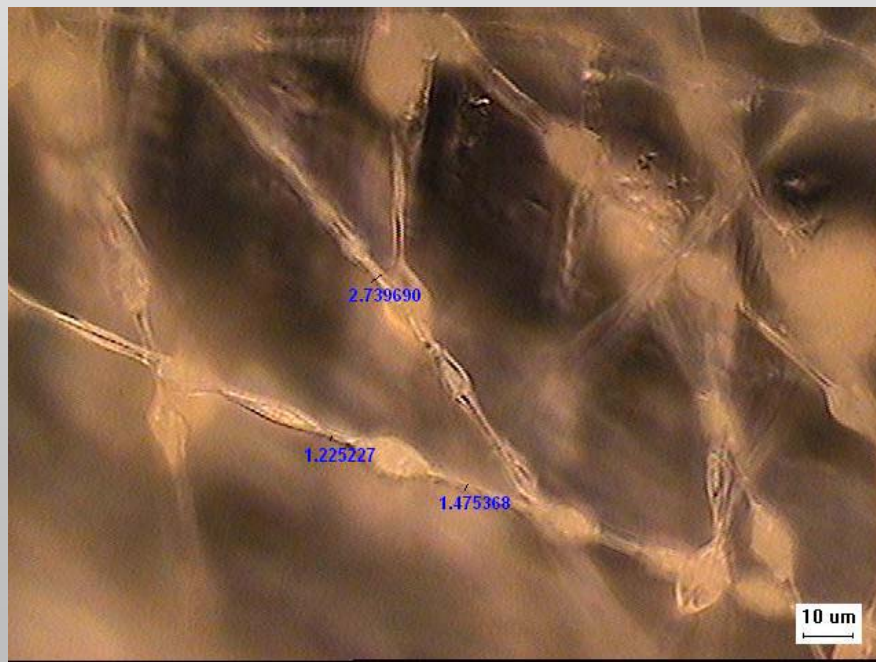
Paper CC4.2

Spring 2010 MRS Meeting  
February 8, 2010



# Outline

- 1) Si Anodes for LIBs
- 2) Liquid Silanes – Cyclohexasilane Chemistries
- 3) Electrospinning a-Si NWs using PMMA as a carrier
- 4) Half-cell testing
- 5) Electrospinning *porous* a-Si NWs using QPAC100®
- 6) Future work



# Nano-Si as Li Ion Battery Anode

>10-fold increase in energy density (+)

$\text{Li}_x\text{C}_6$  372 mAh/g vs.  $\text{Li}_{22}\text{Si}_5$  ~4200 mAh/g

300% volume expansion during charge (-)

Address mechanical instability by “going nano”

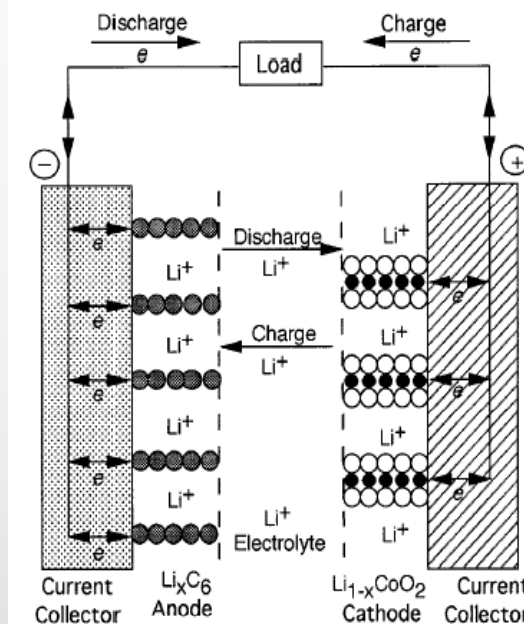


Table 1. A list of Some Si-Based Anode Technologies Being Explored for LIB in PHEV.

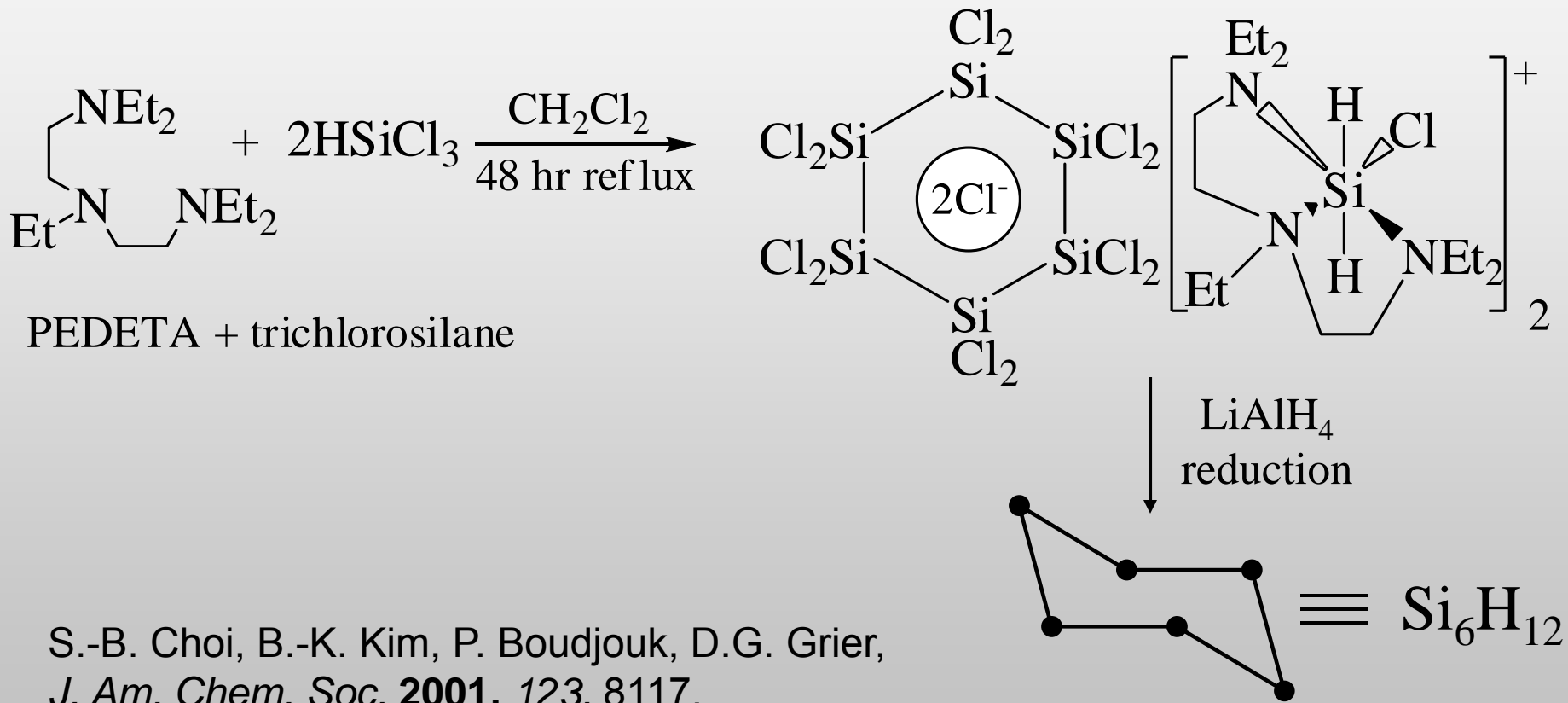
Entity	Anode Type	<u>mAh/g</u>	Benefits/Drawbacks	F
C. Mellon	Si/C/SWNT's	1066	Low cycling losses (+) not easily scalable (-)	
Montpellier	Ag-Si	1488	High capacity (+); high cost, difficult to scale (-)	
Stanford	<u>SiNWs/Au-Si</u>	1000	High capacity (+); high cost, difficult to scale (-)	
SUNY-SB	Si/C	500	High carbon content, limited capacity (-)	
PNNL	VI-SLS <u>SiNWs</u>	1300	Not easily scalable (-)	
U-Pitt	Si/C/PC	1015	High temp process (-)	
Kiev Nat'l	Si/C	1235	Scalable process (+); capacity fade (-)	
Ulsan Nat'l	<u>Si Nanotubes</u>	3247	Low loss for 200 cycles (+); difficult to scale (-)	
A123	C	320	Thermal stability (+); limited capacity (-)	
Preliminary at NDSU	E-spun <u>SiNWs</u>	414	Scalable process, low cycling loss and decent capacity for 1 <sup>st</sup> attempt (+); unproven (-)	

Figure from Cui, Y. "Nanotechnology-Enabled Memory and Energy Applications"

<http://www.caiss.org/docs/Presentation/CAISSDinnerSeminar041708.pdf> 04/17/2009

# Cyclohexasilane Si<sub>6</sub>H<sub>12</sub> Chemisty

## Amine-promoted disproportionation and redistribution: Si-Si bond formation



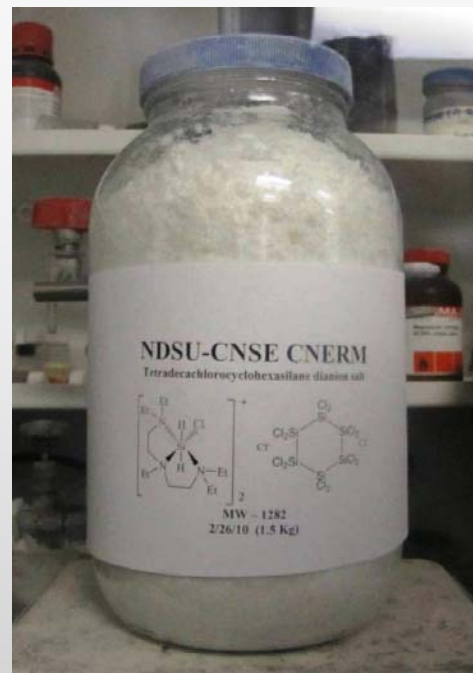
S.-B. Choi, B.-K. Kim, P. Boudjouk, D.G. Grier,  
*J. Am. Chem. Soc.* **2001**, 123, 8117.

bp. ~ 220 °C  
(80 ° C/10 mTorr)  
mp. 18 °C  
ρ 0.97 g/mL

# Si<sub>6</sub>H<sub>12</sub> Production at NDSU

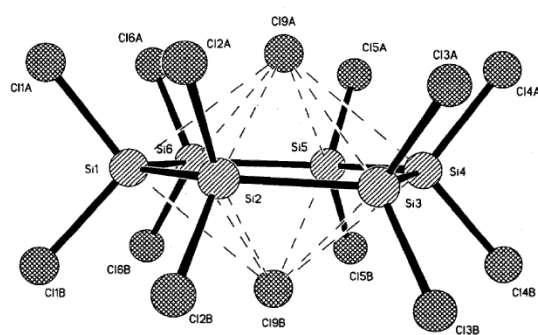
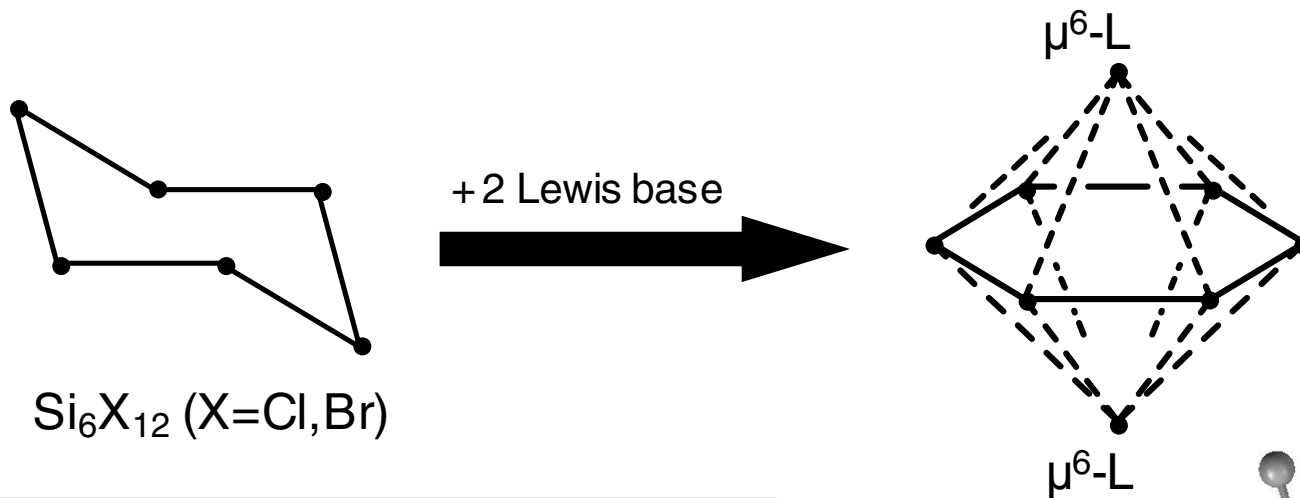
- Production level is now 10 g/week.
- 2 kg/day facility envisioned.
- Discussions with several manufacturers of fine chemicals for the semiconductor industry ongoing.

Having Si<sub>6</sub>H<sub>12</sub> in-house offers a competitive advantage

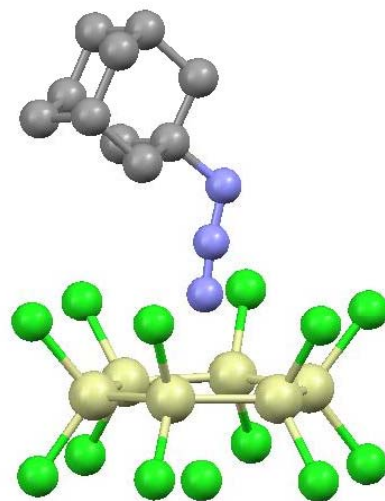




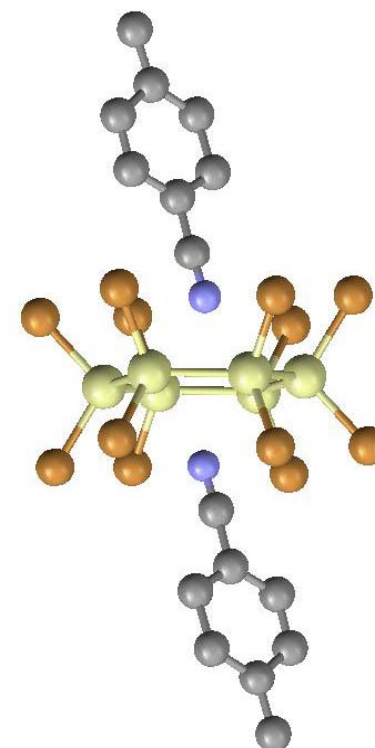
# “Inverse Sandwich” Complexes of Perhalocyclohexasilane



Dianion  $\text{Si}_6\text{Cl}_{12}(\text{Cl}_2)^{2-}$

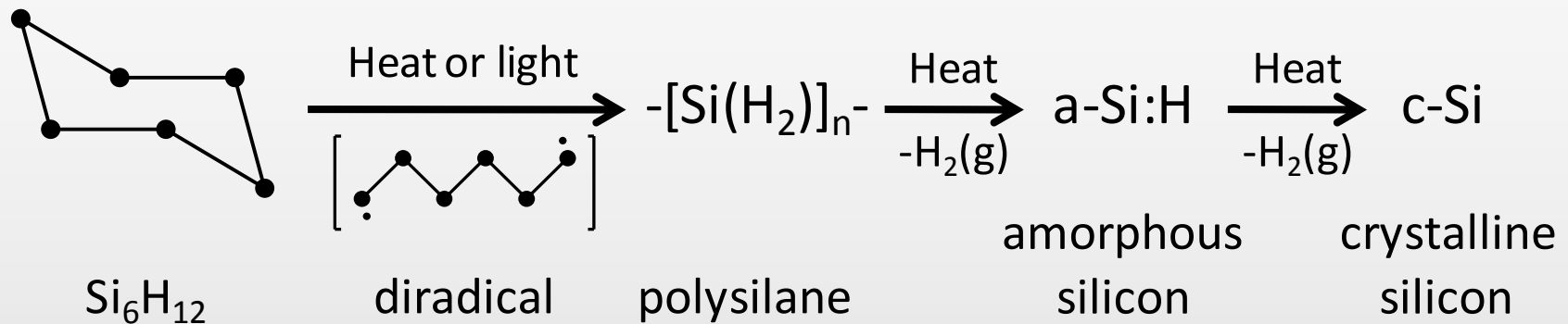


Monoanion  $\text{LSi}_6\text{Cl}_{12}(\text{Cl})^-$

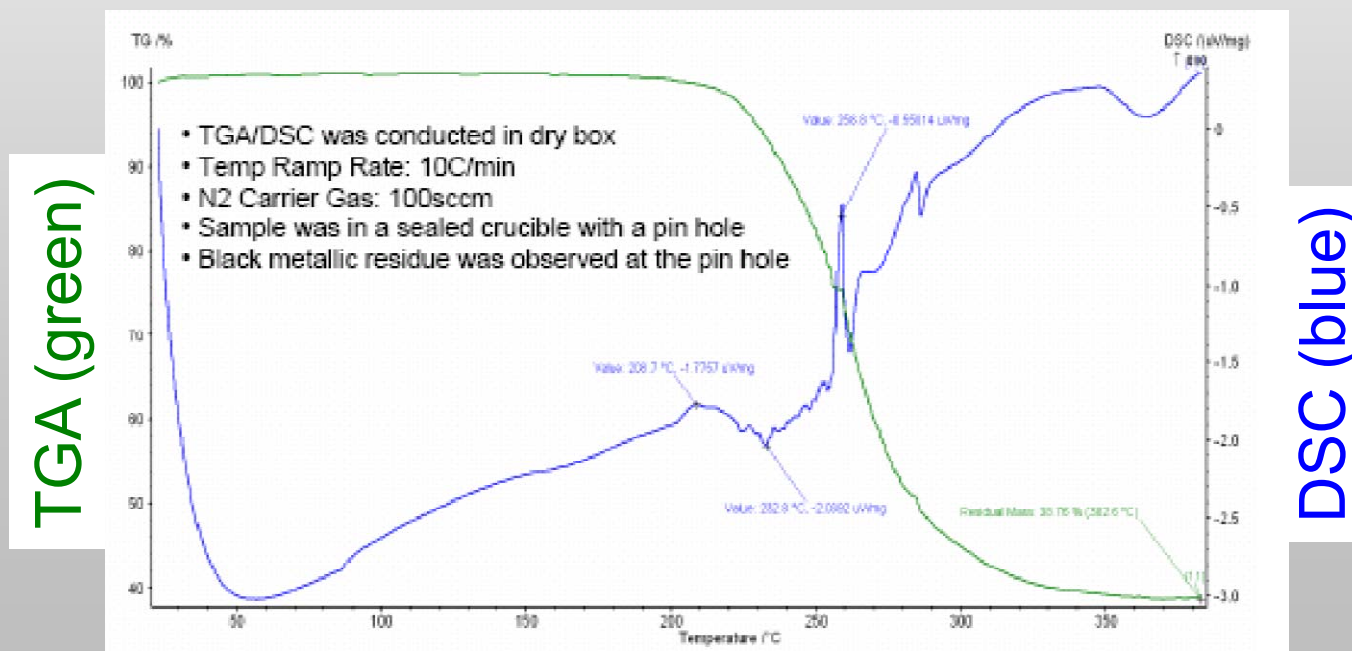


Neutral  $\text{L}_2\text{Si}_6\text{Br}_{12}$

# Si<sub>6</sub>H<sub>12</sub> as a Precursor to Si-based Electronic Materials



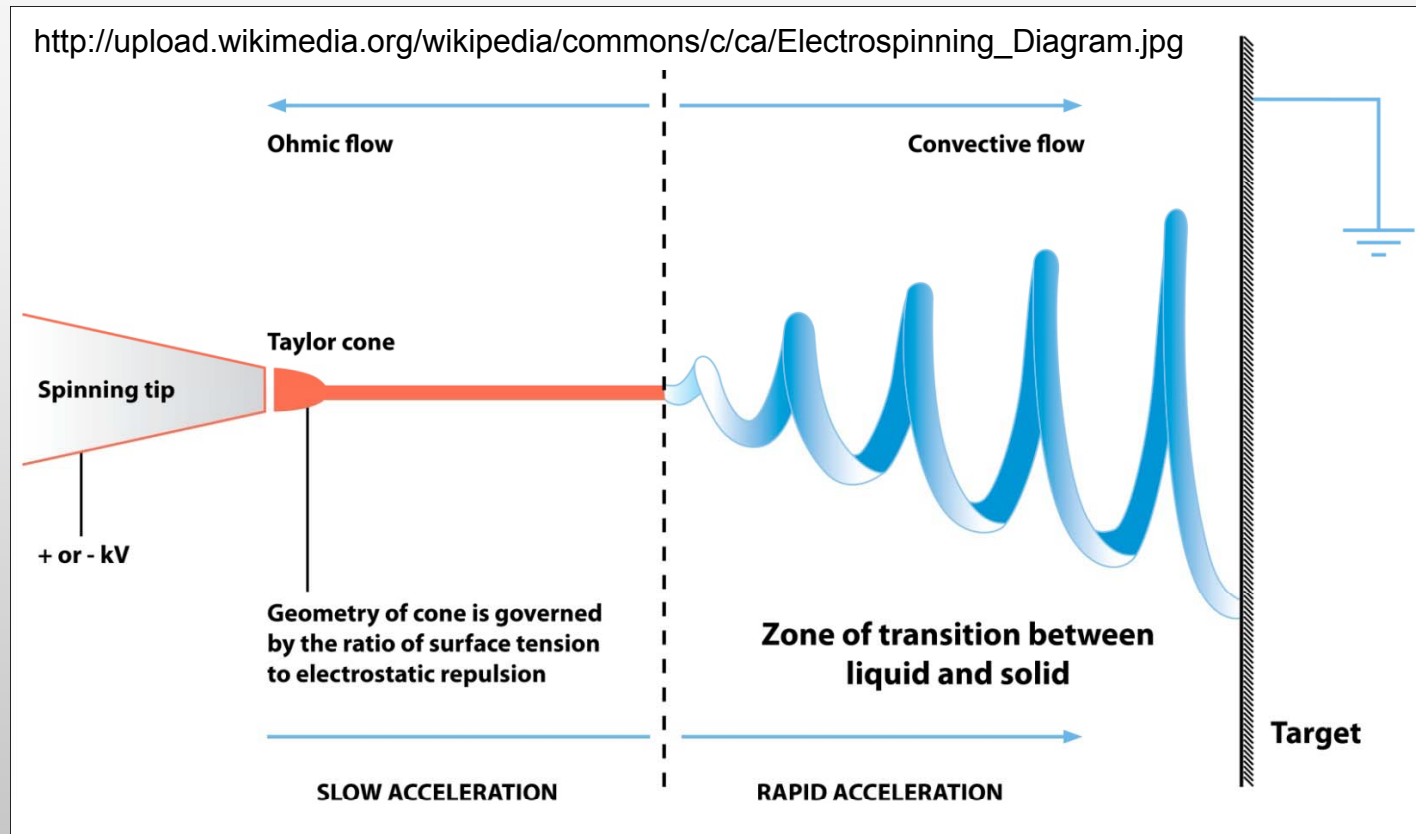
## Si<sub>6</sub>H<sub>12</sub> is Relatively Thermally Stable



Isothermal TGA at 100 °C shows no weight change after 12 h

# Electrospinning Yields Nanowires

diameters from 1 to 2000 nm



Synthetic and natural polymers

Ceramics

Carbon

Semiconductor materials

D.H. Reneker, A.L. Yarin, et al, *Adv. Appl. Mech.*, **41**, 43-195 (2007).

D.H. Reneker and A.L. Yarin, *Polymer*, **49**, 2387 (2008).

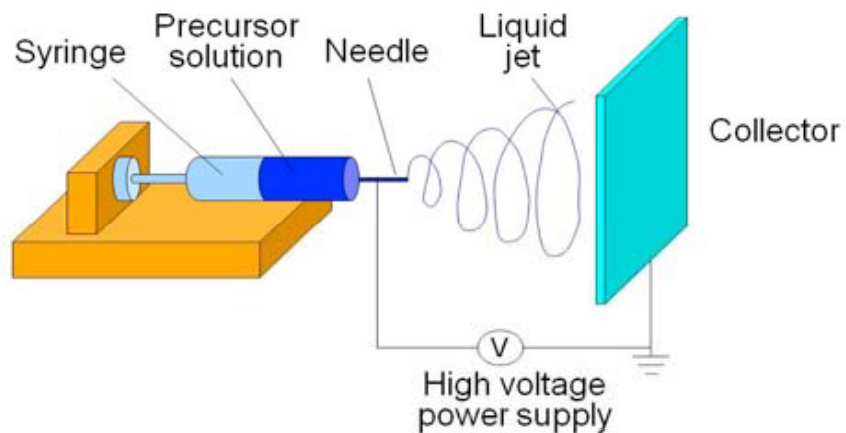
D. Li and Y. Xia, *Adv. Mater.*, **16**, 1151 (2004).

C. Lai, D.H. Reneker et al., *Nanotechnology*, **19**, 195303 (2008).

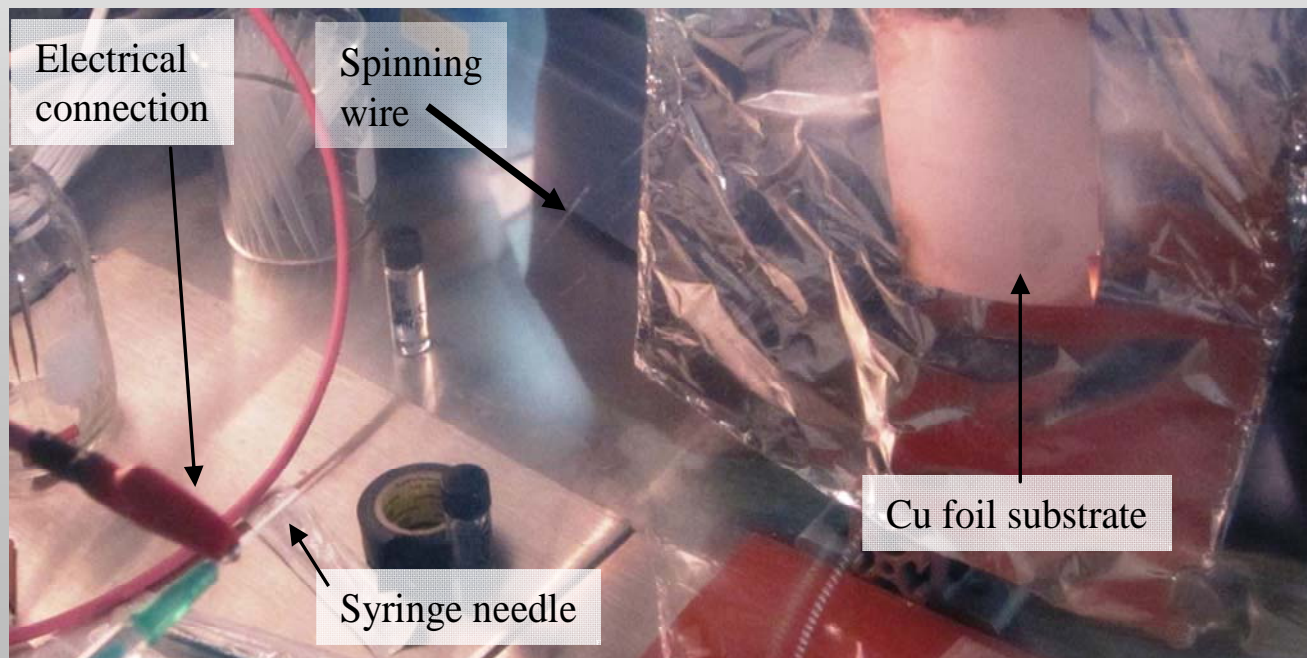
R. Ramaseshan, et al., *J. Appl. Phys.*, **102**, 11101 (2007).



# NDSU-CNSE Electrospinning Setup



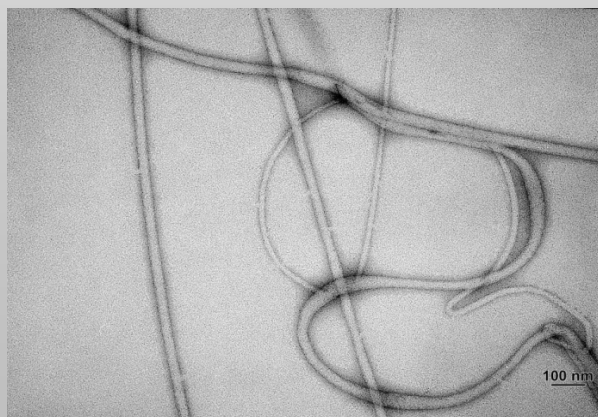
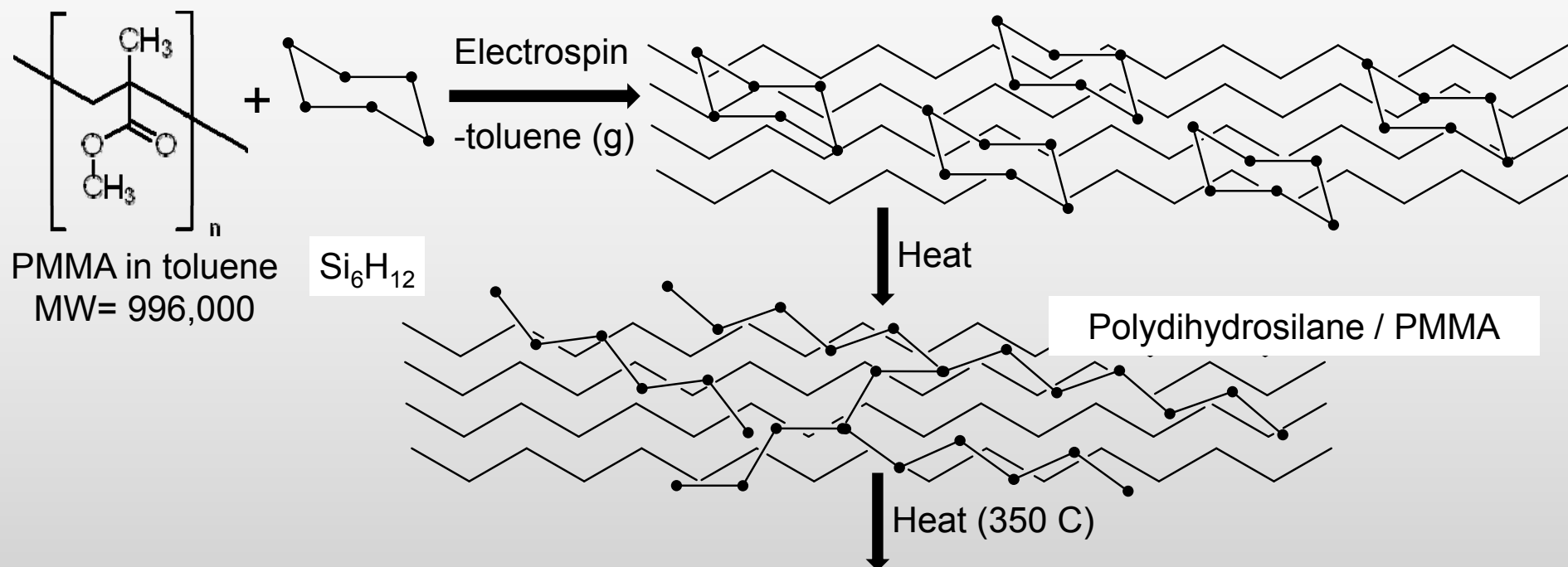
Located inside inert glovebox



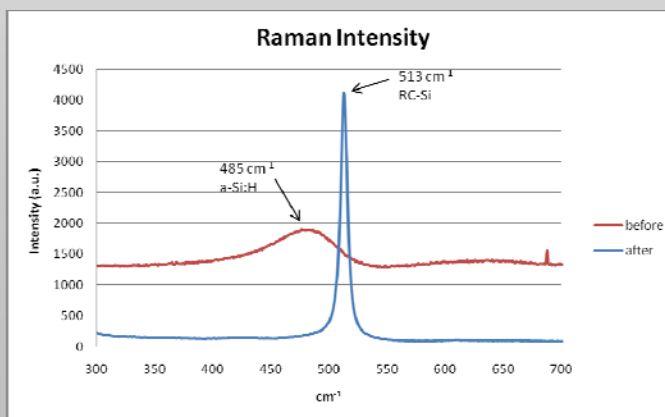
# **Electrospinning Liquid Silanes**

**QuickTime Movie**

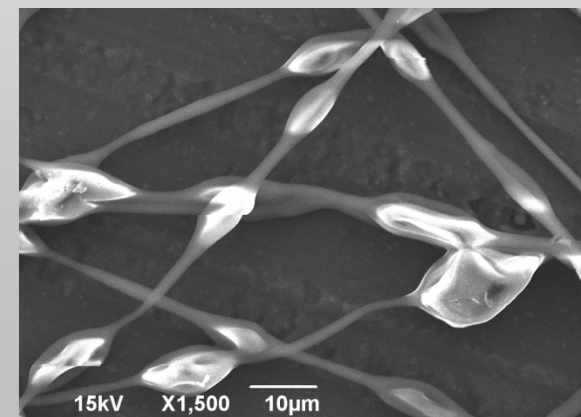
# 1<sup>st</sup> Gen Ink. PMMA in Toluene, Add Si<sub>6</sub>H<sub>12</sub>, Electrospin, Thermolysis



TEM micrograph shows nanowire diameters of 16 to 33 nm



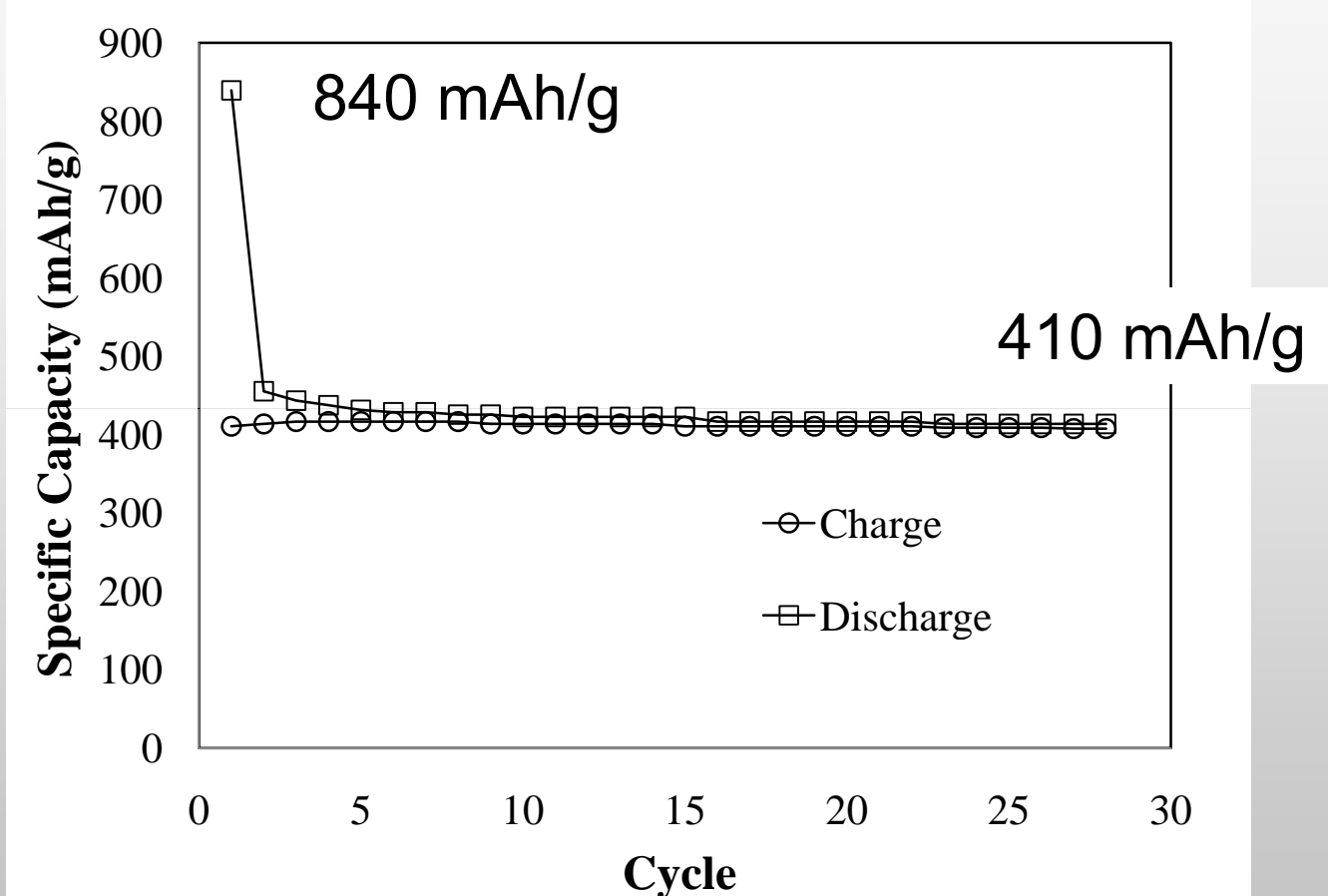
a-Si:H / PMMA  
[Note: Raman laser rc-Si]



SEM showing beads – initial formulation

# Electrochemical Testing of Li<sup>0</sup>/a-SiNW Half-Cell

Electrospun a-SiNWs are resilient to cell cycling



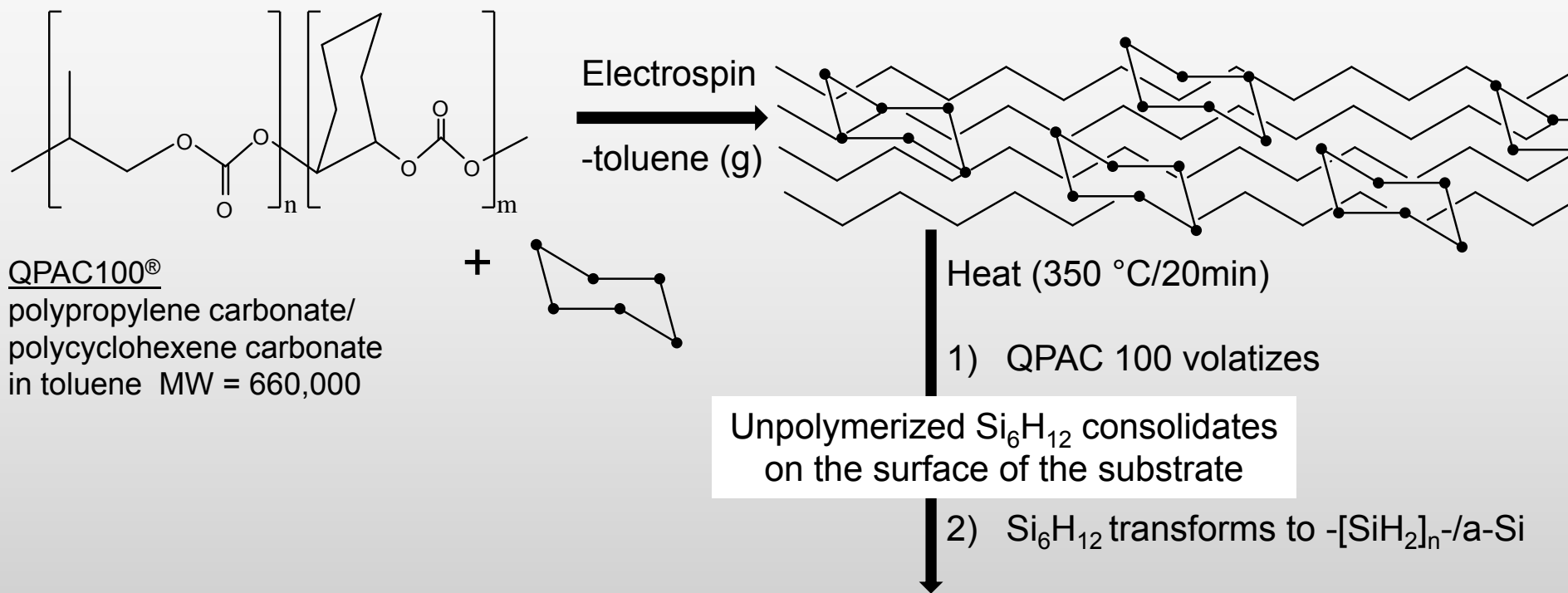
specific discharge capacity decreases only 9.2% from 2<sup>nd</sup> to 30<sup>th</sup>

Celgard 2300

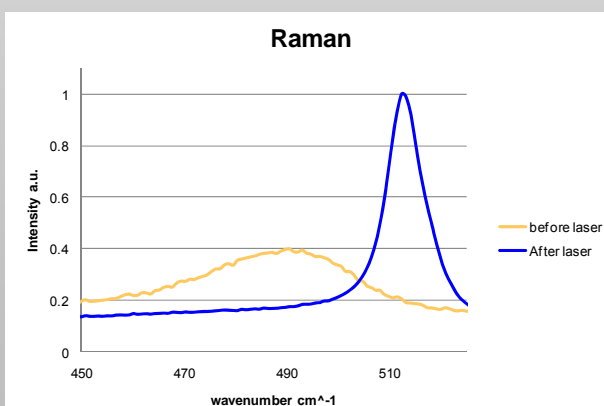
1M LiPF<sub>6</sub> in (ED:DEC = 1:1)

Cycled between 0.02 and 1.50 V at 100 mA/g

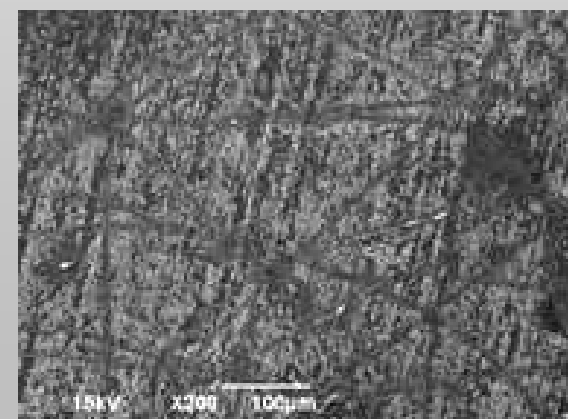
## 2<sup>nd</sup> Gen Ink. QPAC100<sup>®</sup> in Toluene, Add Si<sub>6</sub>H<sub>12</sub>, Electrospin, Thermolysis



Optical photograph

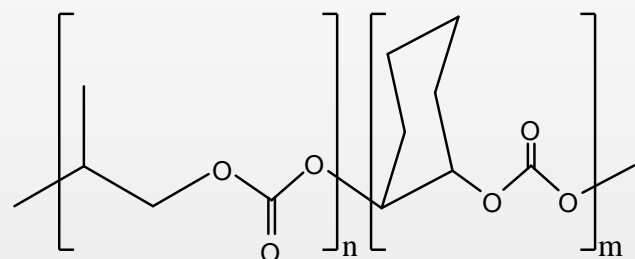


a-Si:H / PMMA  
 [Note: Raman laser rc-Si]

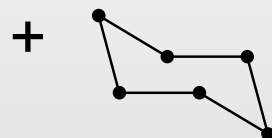


SEM micrograph

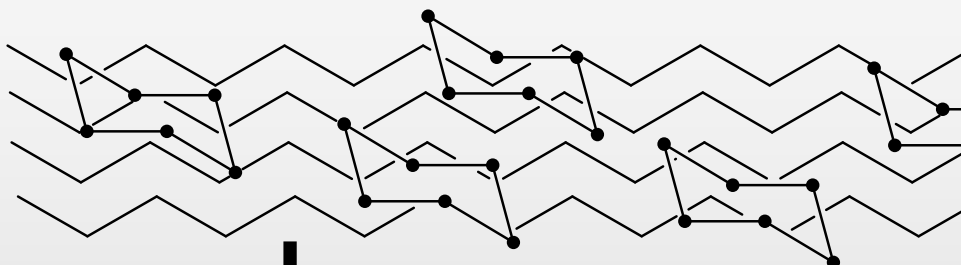
## 2<sup>nd</sup> Ink'. QPAC100<sup>®</sup>/Toluene/Si<sub>6</sub>H<sub>12</sub>, E-spin, Laser Treatment, Thermolysis



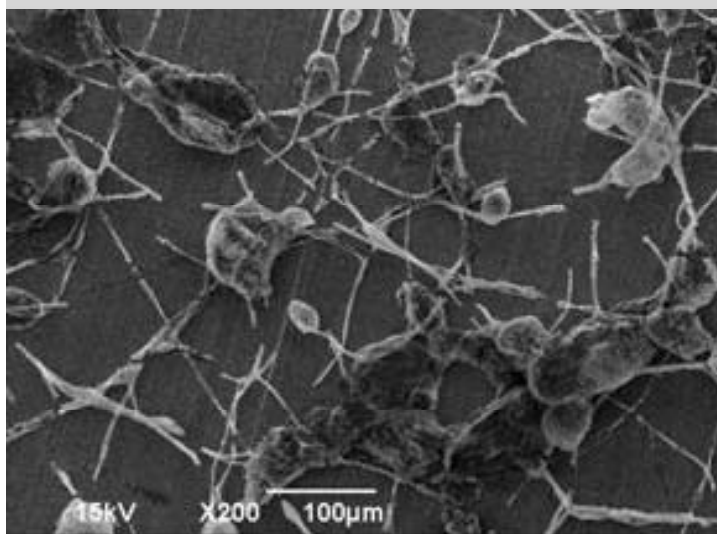
QPAC100<sup>®</sup>  
polypropylene carbonate/  
polycyclohexene carbonate  
in toluene MW = 660,000



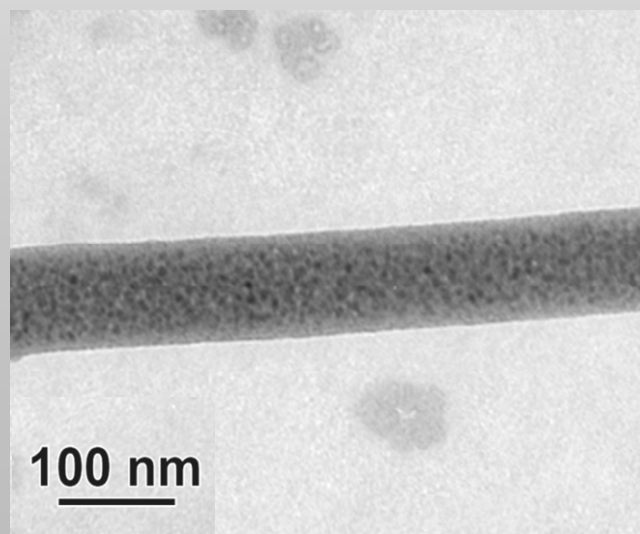
Electrospin  
→  
-toluene (g)



Laser (355 nm @ ~250mW/cm<sup>2</sup>)  
1) Si<sub>6</sub>H<sub>12</sub> transformed to -[SiH<sub>2</sub>]<sub>n</sub>-  
Heat (350 °C/20 min)  
2) QPAC 100<sup>®</sup> volatilizes  
3) -[SiH<sub>2</sub>]<sub>n</sub>- transformed to a-Si



SEM micrograph



TEM micrograph

Porous  
a-Si NWs



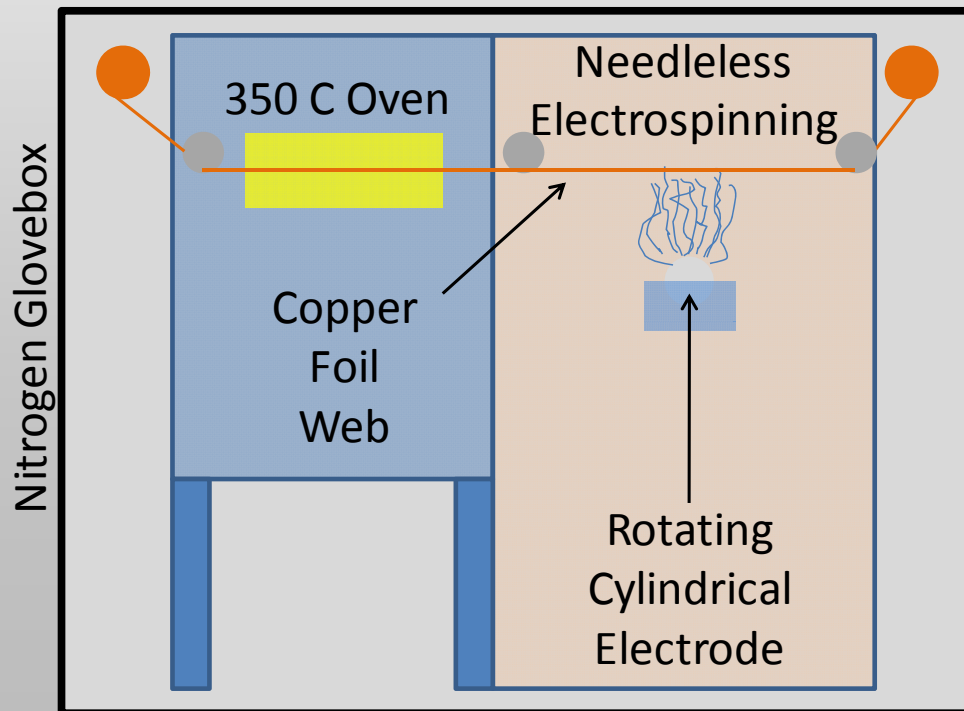
## Future Plans

Scaleup  $\text{Si}_6\text{H}_{12}$  production

Refine single-needle electrospinning of  $\text{Si}_6\text{H}_{12}$

Isolate conducting a-SiNWs using doped inks

Transition to needleless  $\rightarrow$  Cu anode coated with a-Si NWs



**A plug-in process  
for manufacture ?**

**NanoSpider by**



## Conclusions

**NDSU produces  $\text{Si}_6\text{H}_{12}$  toward pilot scale**

**$\text{Si}_6\text{H}_{12}$  can be electospun using a polymer carrier**

**First a-Si nanowires**

**First *porous* a-Si nanowires**

**Initial battery testing similar to crystalline SiNWs**

# NDSU SiLiSiXErS

## ★ 2009 All Star Team ★

<b>Xuliang Dai</b>	<b>Jon Tolstedt</b>
<b>Matt Robinson</b>	<b>Dennis Anderson</b>
<b>Jake Fink</b>	<b>Pooja Vaidya</b>
<b>Chris Braun</b>	<b>Josh Huether</b>
<b>John Lovaasen</b>	<b>Joy Goswami</b>
<b>Chris Olson</b>	<b>Kostia Pokhodnya</b>
<b>Xiangfa Wu</b>	<b>Samy Elangovan</b>
<b>Cody Gette</b>	<b>Kendric Nelson</b>
<b>Iskander Akhatov</b>	<b>Drew Thompson</b>
<b>Justin TT Hoey</b>	<b>Orv Swenson</b>
<b>Larry Pederson</b>	<b>Danielle Vaughn</b>
<b>Kenny Anderson</b>	<b>David Givers</b>
<b>Doug Schulz</b>	<b>Laura Slicer</b>
<b>Kristen Keller</b>	<b>Rob Sailer</b>
<b>Jeremiah Smith</b>	<b>Guru Srinivasan</b>
<b>Joe Chapman</b>	<b>Kyle Johnson</b>
<b>Dale Zetocha</b>	<b>Mark Simon</b>
<b>Steve Andrie</b>	<b>Cono Pavone</b>
<b>Phil Boudjouk</b>	<b>Byron Dorgan</b>

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